

**IN THE SPECIFICATION**

At page 5, please replace the paragraph beginning at line 16 with the following:

The system measures output from each of the 76 elements in the array and calculates the center of mass for the entire arrangement. The relative power of the beam being Gaussian dictates that the arrays be sized such that the expected bandwidth spans several array elements, including spanning two, three, or more array elements. The system operates by scanning the wafer and monitoring movement of the retro beam from expected. In operation, the present design may offer an ability to detect surface variations of less than approximately 1000 nanometers and surface contours over areas larger than particles or scratches.